IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:

Yuichi MATSUI

Appln. No.:

Filed: Herewith

For: SEMICONDUCTOR DEVICE AND MANUFACTURING METHOD THEREOF

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. § 1.56, and without any assertion as to materiality or prior art effect, the documents listed on the attached Form PTO-1449 are hereby cited.

Documents AJ-AO and BJ-BN on the attached List are cited in the specification, on pages 2-3, and their relevance is indicated therein.

Respectfully submitted,

NHS: 1mb

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Nelson H. Shapiro

Reg. No. 17,095

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April 22, 2004

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FORM PTO-1449					Atty. Docket	No.	App	Appln. No.	
					XA-10070				
LIST OF DOCUMENTS CITED BY APPLICANT									
					Applicant				
					Yuichi MATSUI				
					Filing Date Group			up	
					HEREWITH				
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Examiner Initial		Document Number	Date		Name	Class	Sub- class	Filing Date	
	AA	5,622,888	4/22/97	Sekine et al.		438	398		
	АВ	6,235,572	.5/22/01	Kunitomo et al. Kuge et al. Manabe Hiratani et al. Chazono et al. Nishioka		438	240		
	AC	6,243,255	6/5/01			361	528		
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	AJ	8-139288	5/31/96	JAPAN				abstract	
	AK	2000-12796	1/14/00	JAPAN	- -			abstract	
	AL	2000-82639	3/21/00 JAPAN 6/7/02 JAPAN					abstract	
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	AO	2001-77108	3/23/01	JAPAN				abstract	
OTHER (including author, title, date, pertinent pages, etc.)									
	AP Rosenfeld, D. et al., "Structural and morphological characterization of Nb ₂ O ₅ thin films deposited by reactive sputtering", American Vacuum Society, 1994, pp. 135-139.								
,	AQ	AQ							
	AR		-			-			
Examiner	:			Considered					
EXAMINE	EXAMINER: Initial if reference considered, whether or not citation is in conformance								
with MDED COO. data I lettered constructed, whether of not citation is in conformance									

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

Page 2 of 2 FORM PTO-1449 Atty. Docket No. Appln. No. XA-10070 LIST OF DOCUMENTS CITED BY APPLICANT Applicant Yuichi MATSUI Filing Date Group HEREWITH U.S. PATENT DOCUMENTS Examiner Document Number Date Name Class Sub-Filing Date Initial class BA BB BC BD ΒE BF BG BH ΒI FOREIGN PATENT DOCUMENTS Examiner Document Number Date Country Class Sub-Translation Initial class 5-345663 12/27/93 BJ JAPAN abstract 10-12043 1/16/98 BK **JAPAN** abstract 2001-284158 BL10/12/01 **JAPAN** abstract 8-31951 BM 2/2/96 **JAPAN** abstract 11-330415 11/30/99 BN JAPAN abstract BO OTHER (including author, title, date, pertinent pages, etc.) ΒP

Examiner

Date Considered

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered.

Include copy of this form with next communication to Applicant.

BQ BR